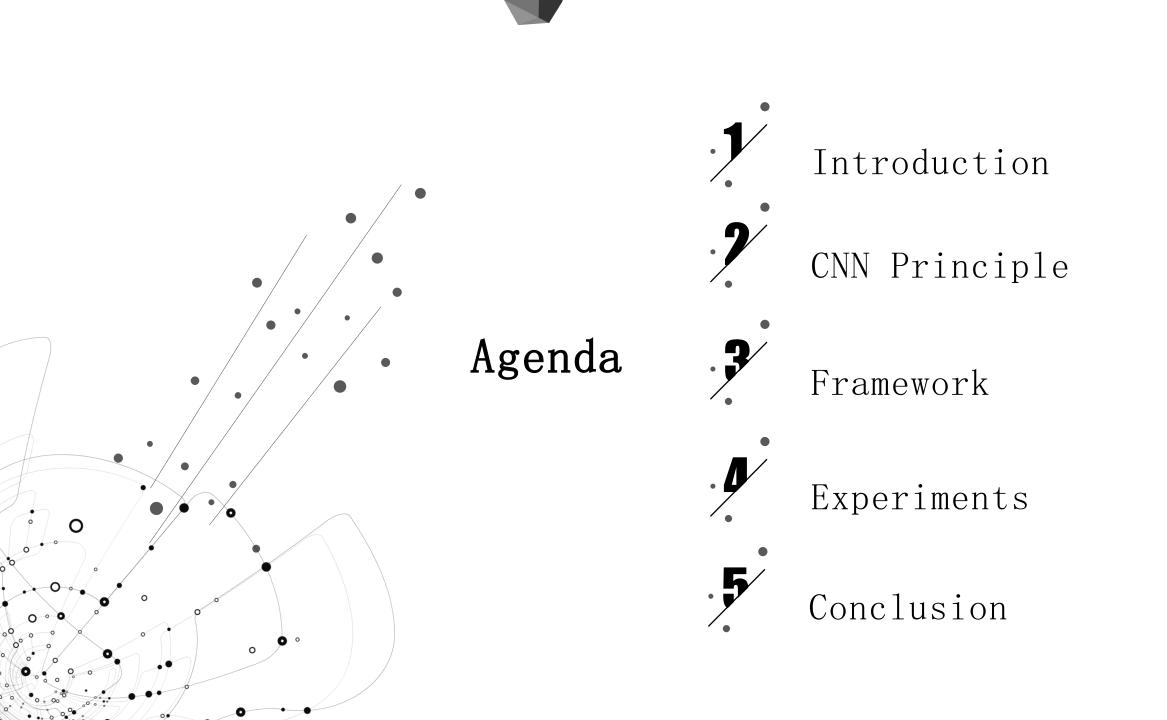
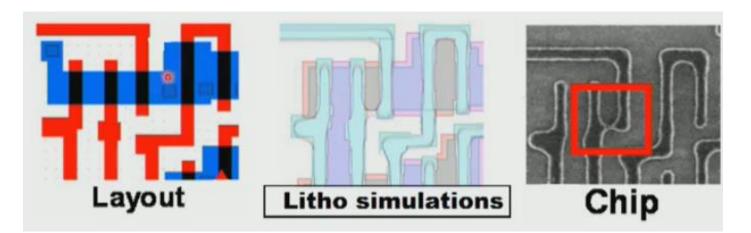
Hotspot Detection of Semiconductor Lithography Circuits Based on CNN

Tongji University

Name: Zhou Xingyu



1. Background Introduction



Node become smaller; Reason hard to track; Slow speed

Machine learning? Deep learning?

Source: Proc. SPIE 10451, Photomask Technology, 104510A

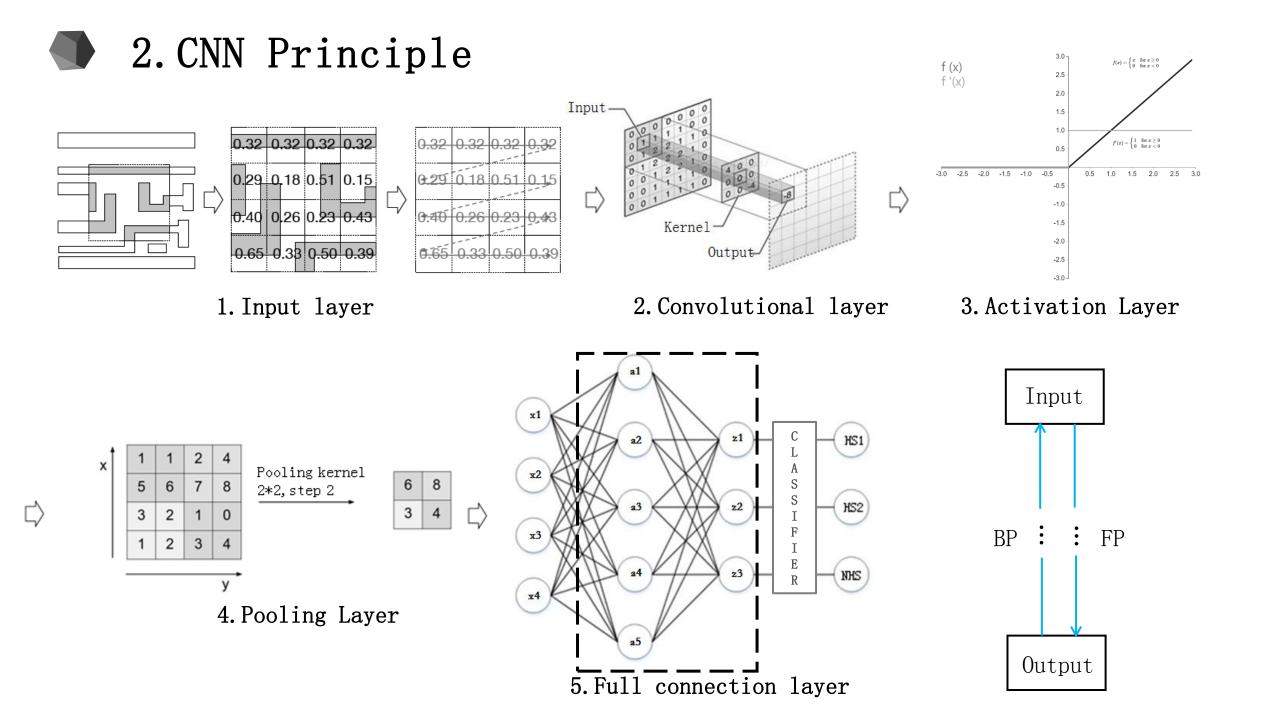
Traditional simulation based defects detection:

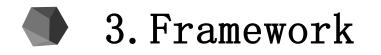
- 1) Slow detection speed.
- 2) Complex algorithms are needed to adapt to different layout.



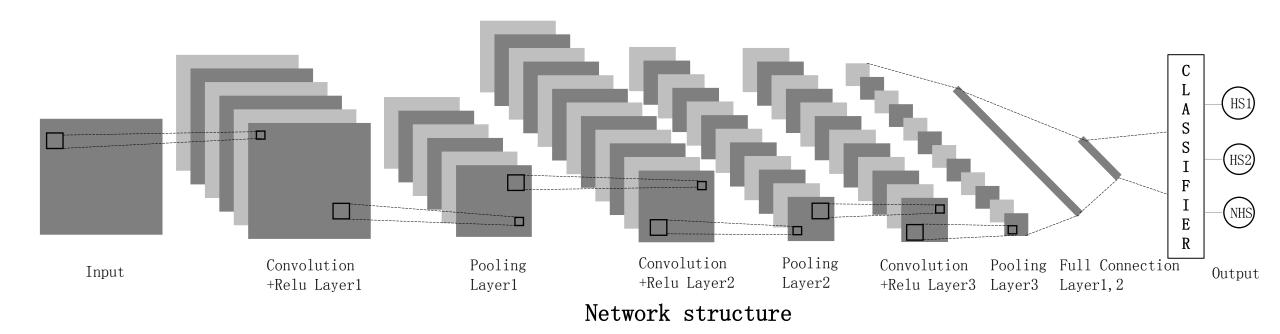
CNN(convolutional neural network) is originally designed to solve the problem of image recognition.

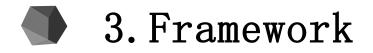
What about Hotspot prediction?

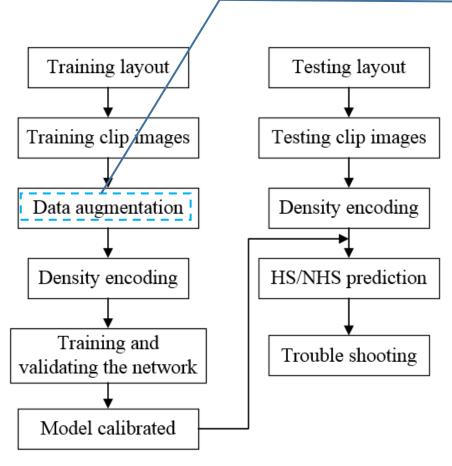




Based on Karas. Karas is a deep learning lib. Highly modularized and extensible.

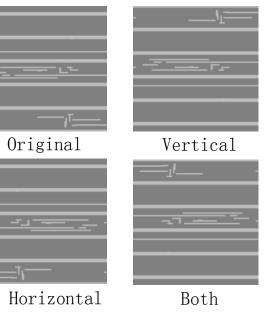






Balance data scale for different classes.

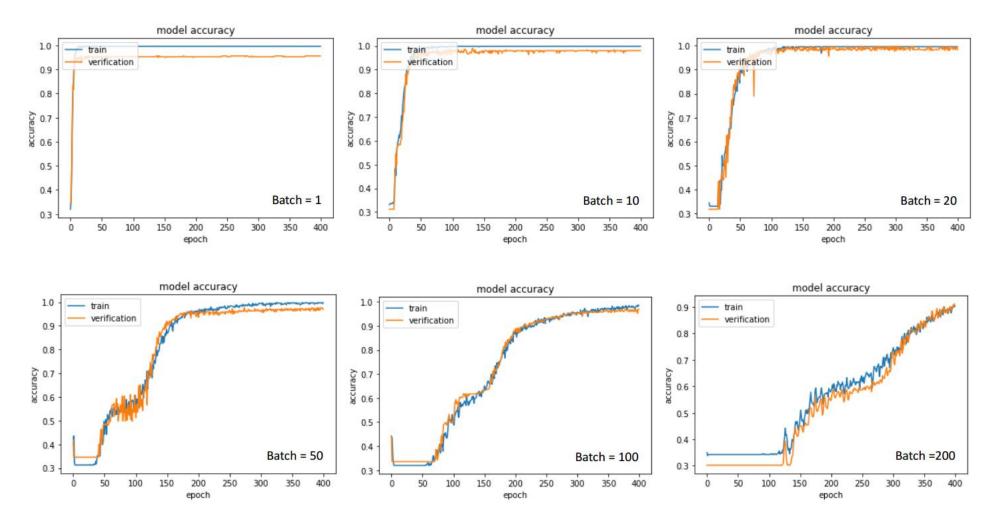
Data augmentation



Work flow

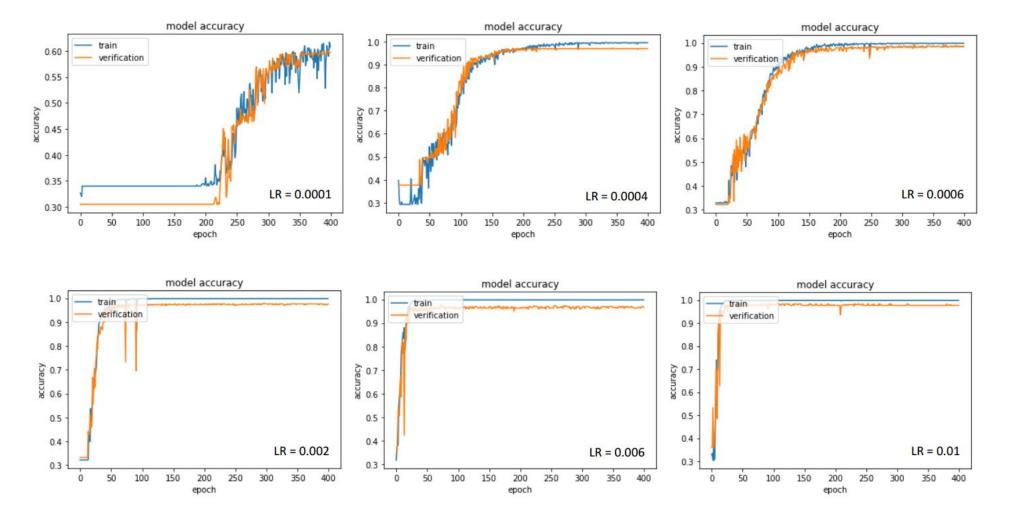


1. Batch size influence



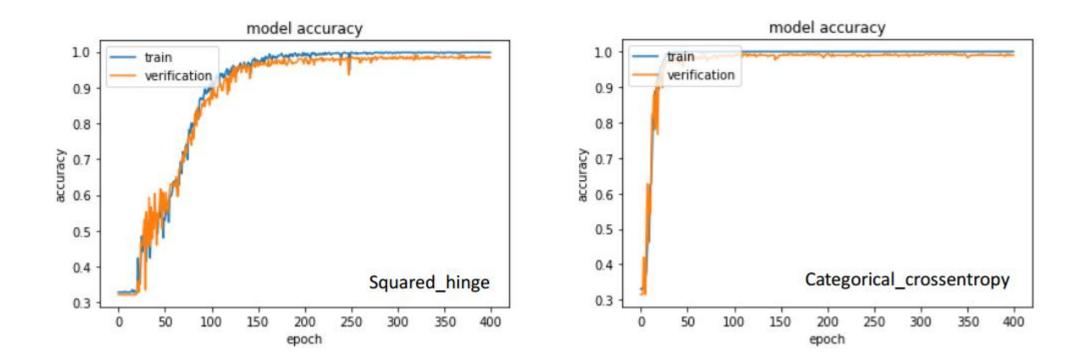


2. Learning rate influence



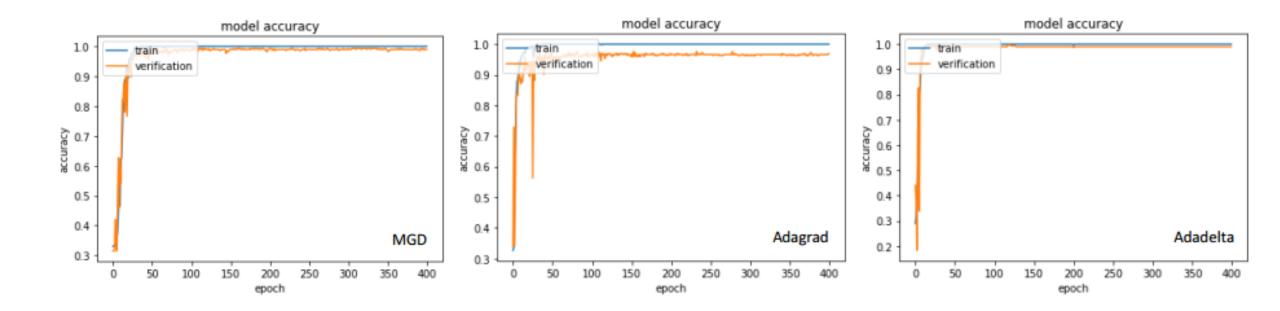


3. Loss function influence





4. Optimization method influence







Start from small network



Tune #epochs and batch size



Tune learning rate



Choose proper loss function and learning method

